

The listing of the claims will replace all prior versions, and listings, of claims in the application:

**Listing of Claims:**

Claims 1-13 (cancelled).

Please cancel claims 14 – 16

Claims 14 – 16 (cancelled).

Claim 17. (currently amended)      A semiconductor wafer process apparatus according to Claim [14] 26 wherein said transfer arm further comprises a lower wafer shelf for carrying a processed wafer and an upper wafer shelf for carrying an unprocessed wafer.

Claim 18. (currently amended)      A semiconductor wafer processing apparatus according to Claim [14] 26 wherein said transfer arm is adopted to simultaneously carry one unprocessed wafer and one processed wafer.

Claims 19-25 (cancelled)

Claim 26. (original)      A semiconductor wafer process apparatus comprising:  
a dual-wafer single-axis transfer arm adapted to carry and transfer semiconductor wafers between a loadlock chamber and a semiconductor wafer process chamber, said transfer arm having a monolithic arm pivotally mounted within said loadlock chamber about a single pivot axis;

wherein said transfer arm is adapted to carry at least two wafers simultaneously between said loadlock chamber and said process chamber; and

wherein said transfer arm comprises a retracted home position and an extended position in which said transfer arm extends into said process chamber, wherein said single pivot axis allows said transfer arm to pivot between said retracted and extended positions.

Claim 27. (original)      The semiconductor wafer process apparatus according to Claim 26 further comprising a cooling plate disposed below said transfer arm when said pivot arm is in said retracted position.

Claim 28. (original)            The semiconductor wafer process apparatus according to Claim 27 wherein said cooling plate further comprises a plurality of lift pins for transporting the wafers between said cooling plate and said transfer arm.

Claim 29. (currently amended)            The semiconductor wafer process apparatus according to Claim[s 14 or] 26 wherein the transfer arm comprises an end effector, said effector comprising an upper shelf and a lower shelf with wafer edge supports thereon respectively and being coupled to the monolithic transfer arm, said effector pivoting with the monolithic arm about said pivot axis.